

FIG.1(A) (1)

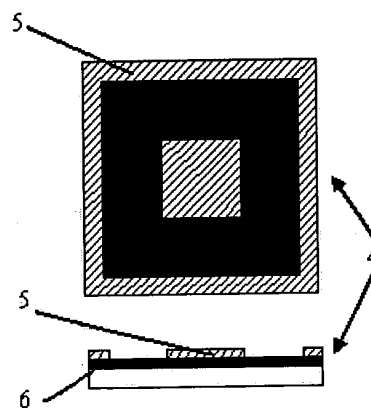


FIG.1(A)(2)

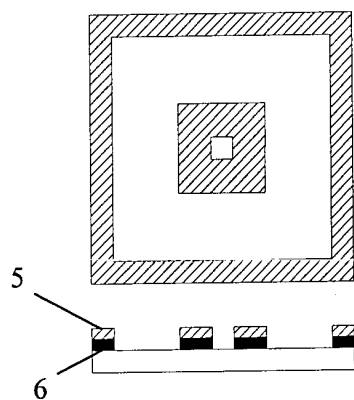


FIG. 1(B)(1)

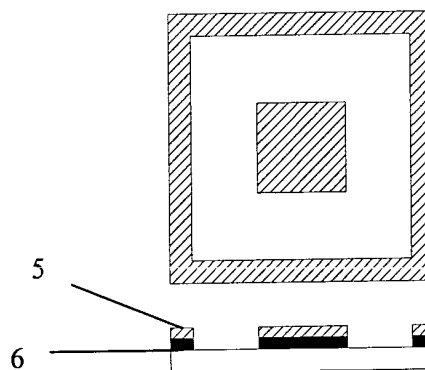
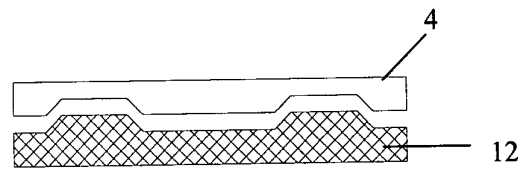
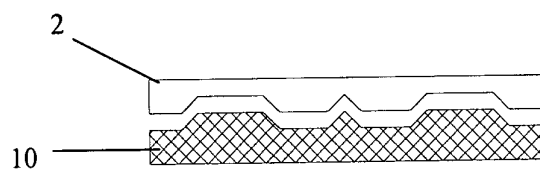
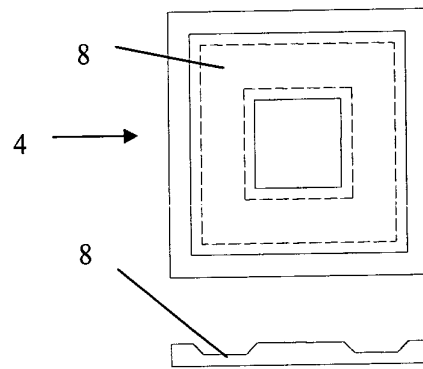
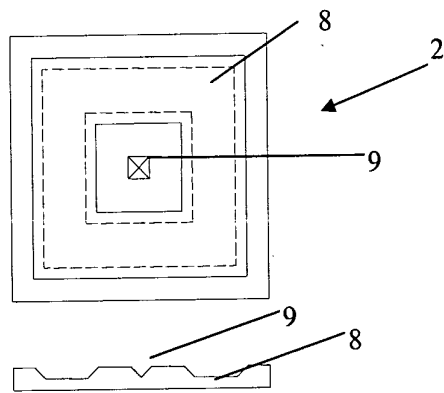
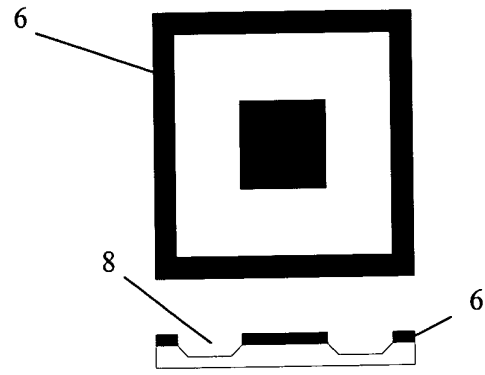
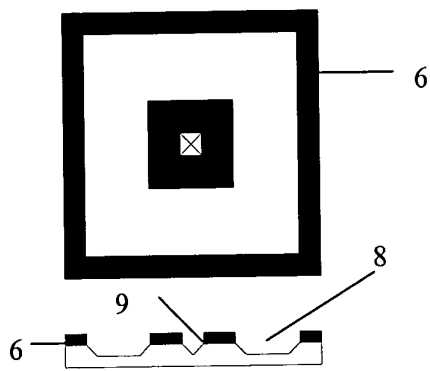


FIG. 1(B)(2)



Si



PMMA

Metal
 PMMA

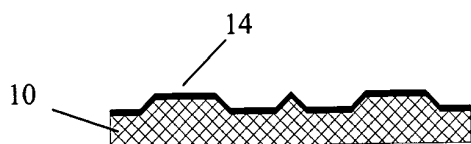


FIG. 1(F)(1)

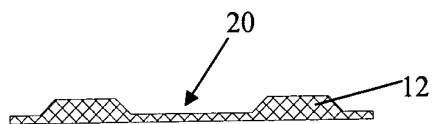


FIG. 1(F)(2)

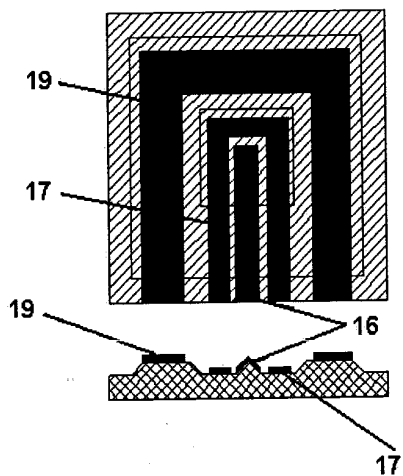


FIG. 1(G)(1)

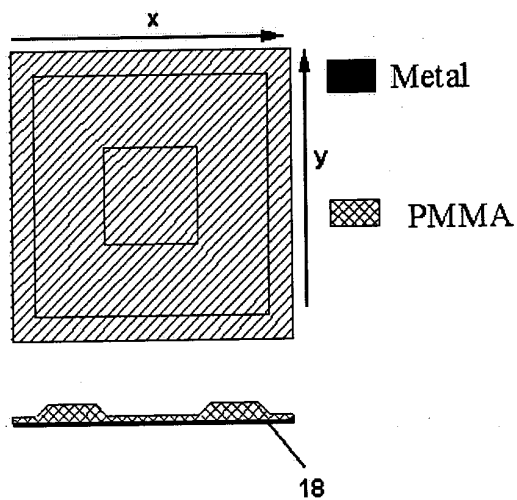
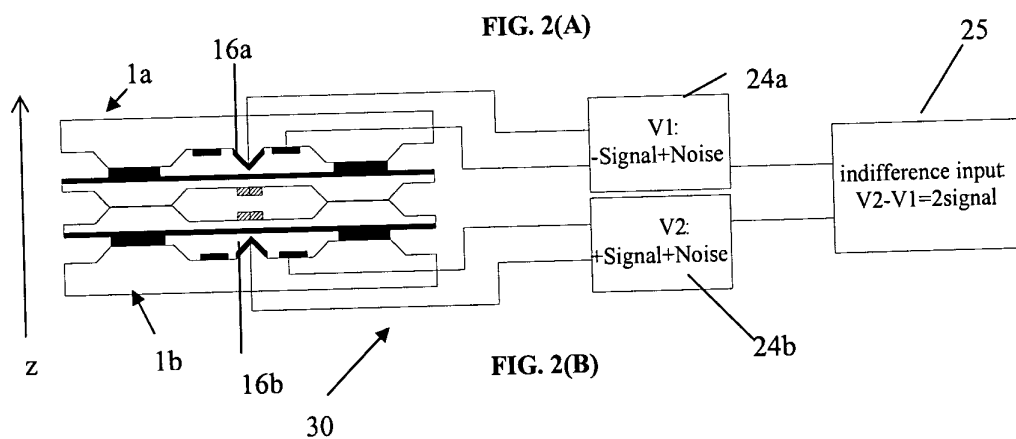
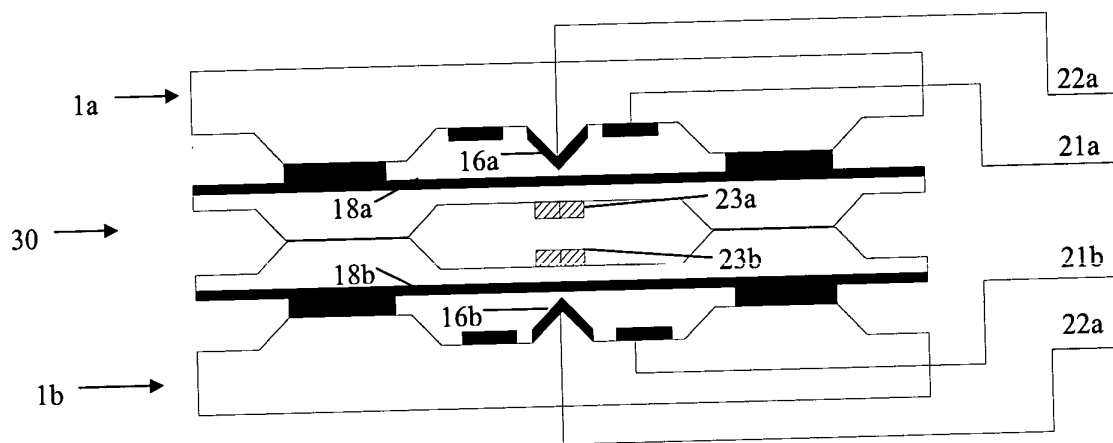
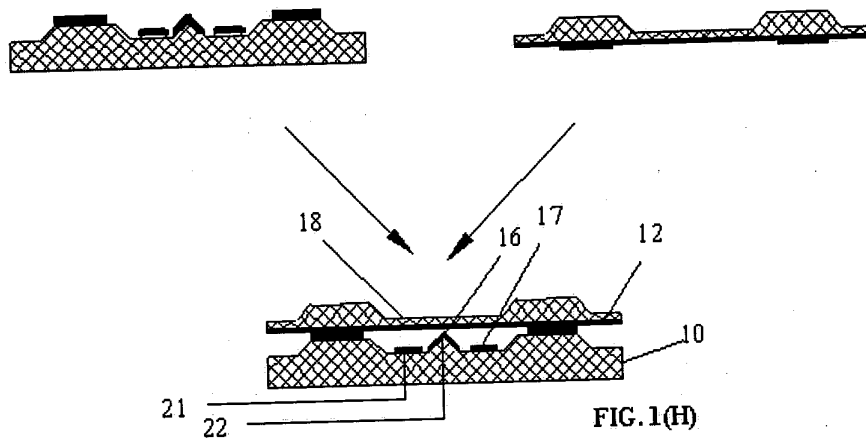


FIG. 1(G)(2)



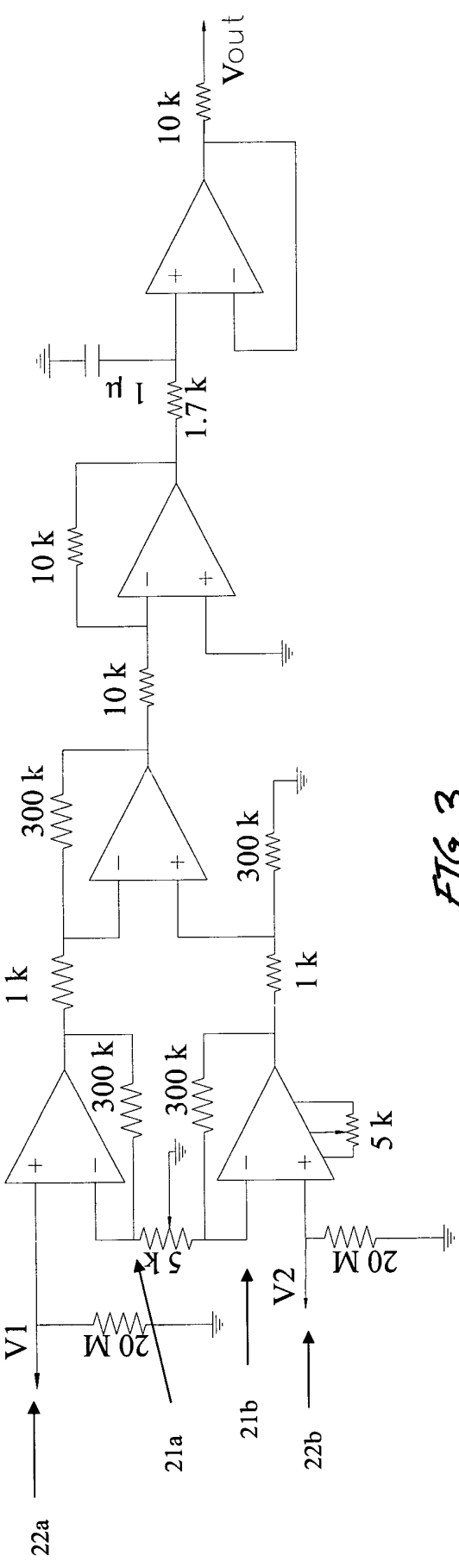
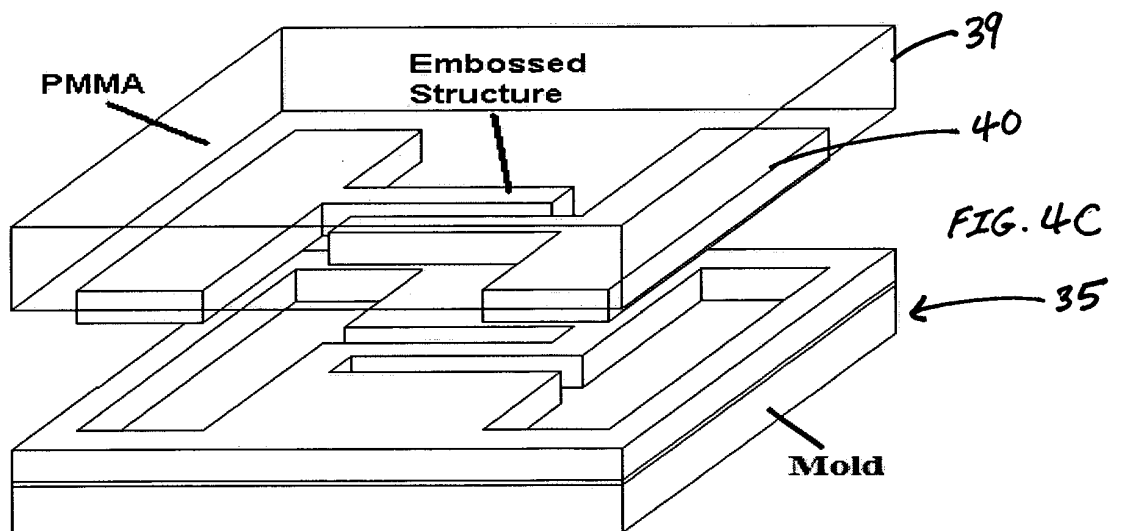
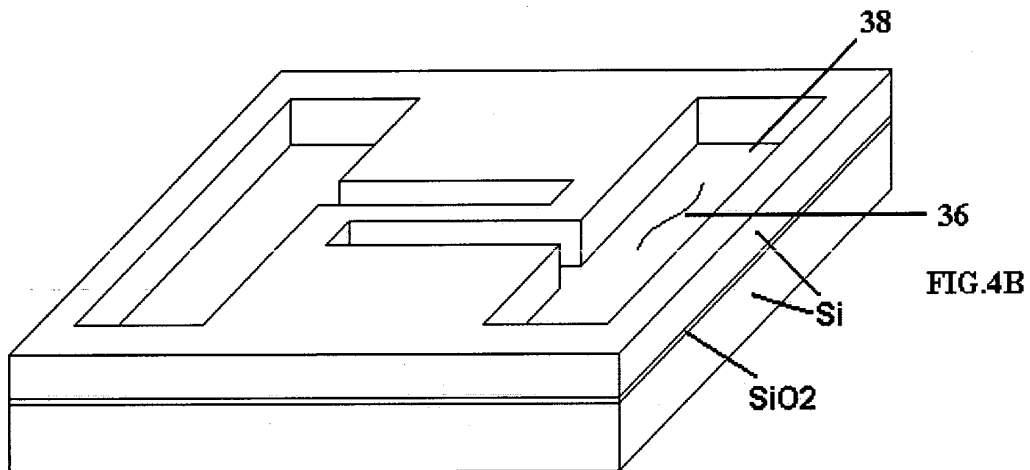
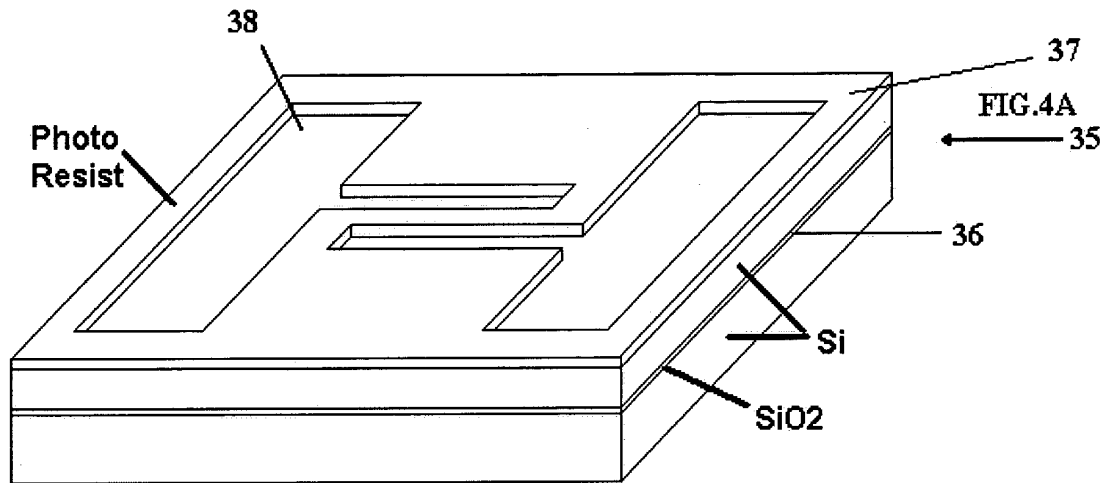
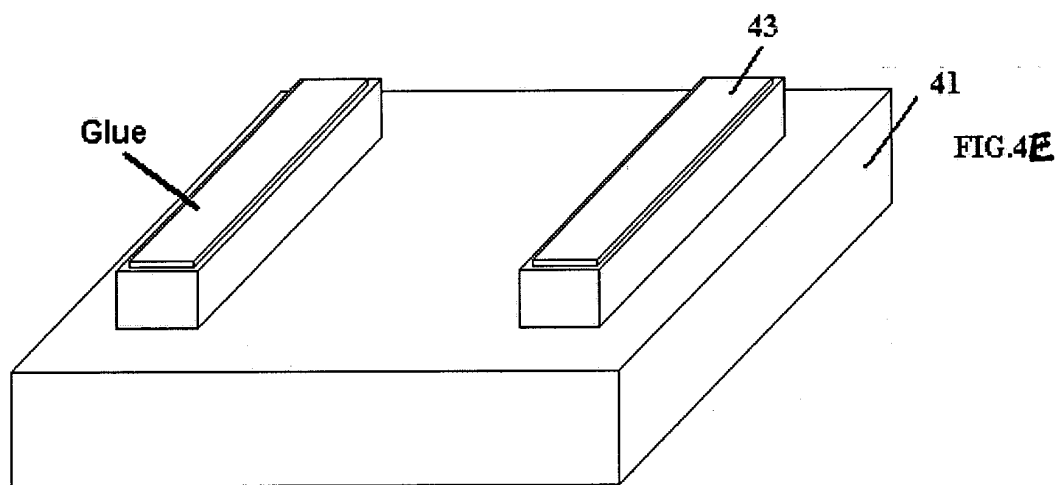
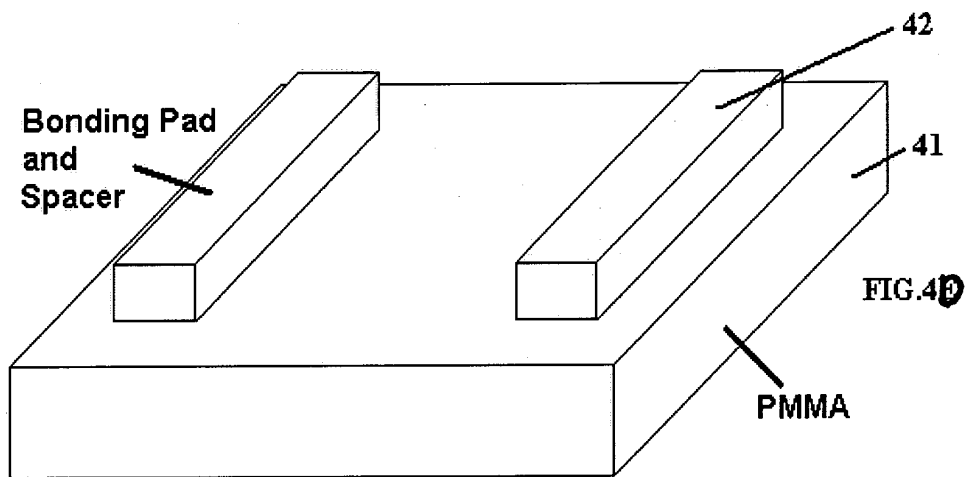
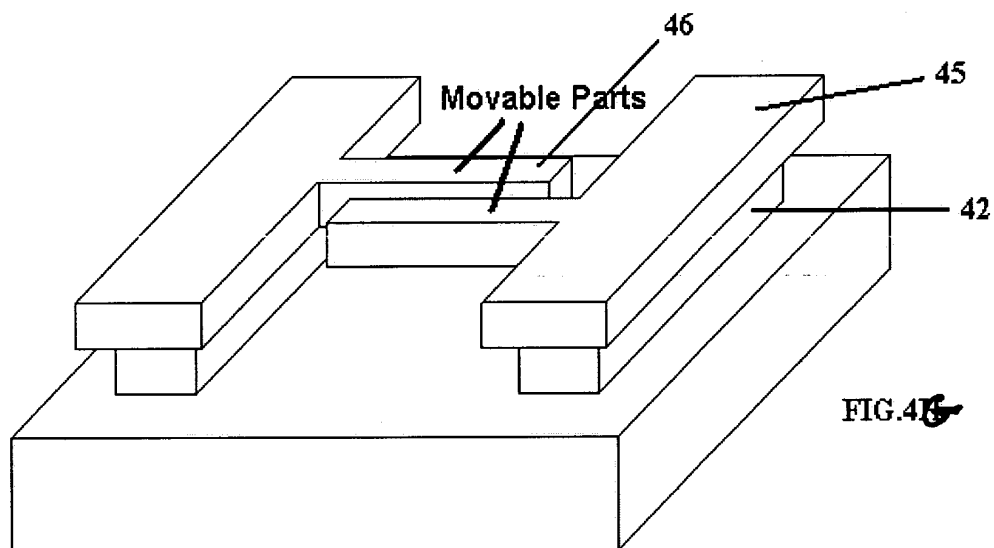
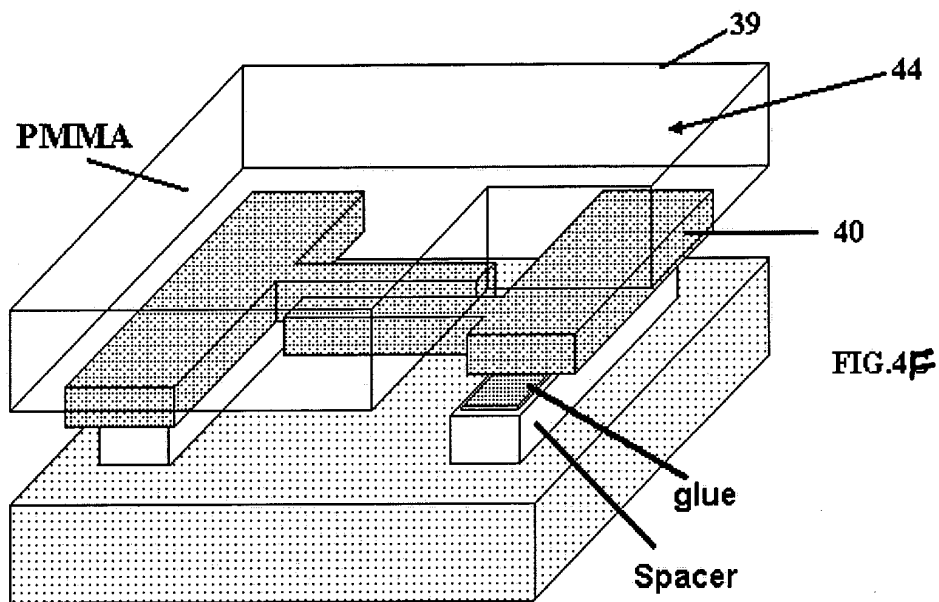


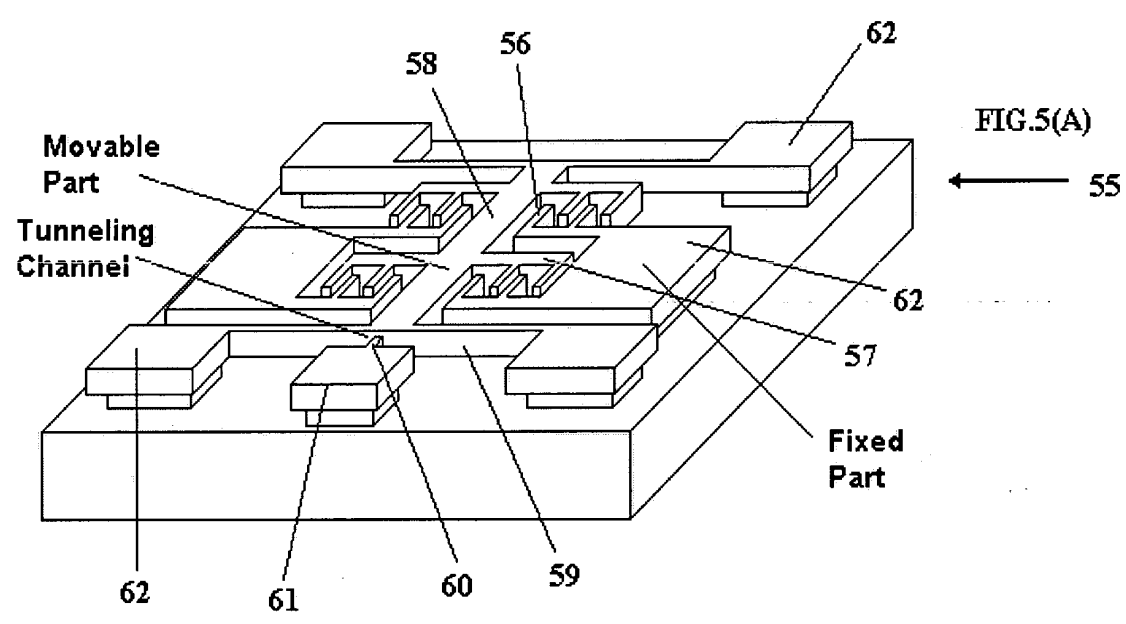
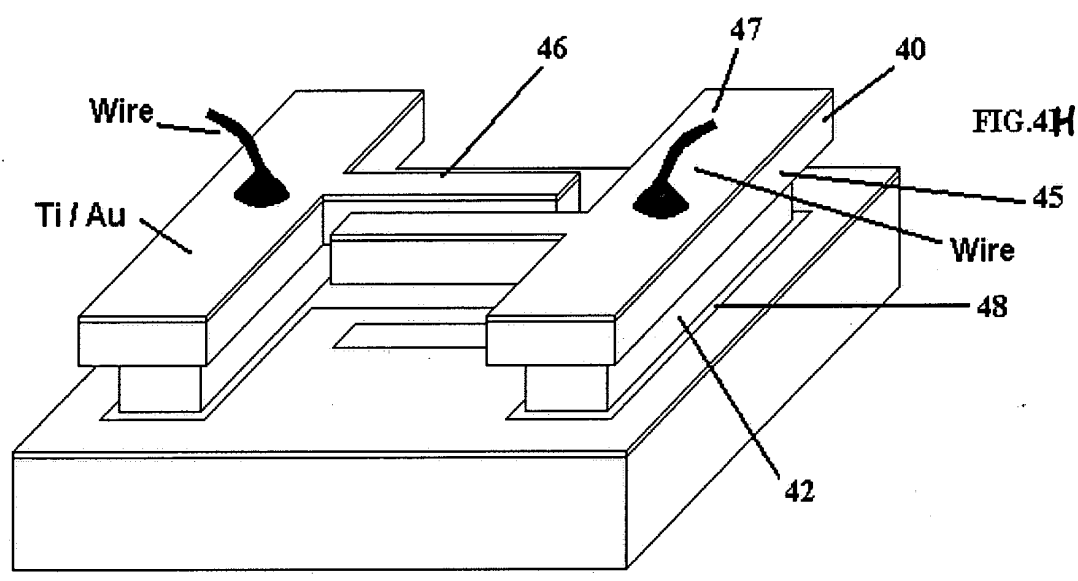
FIG. 3

Process Flow Chart Illustration









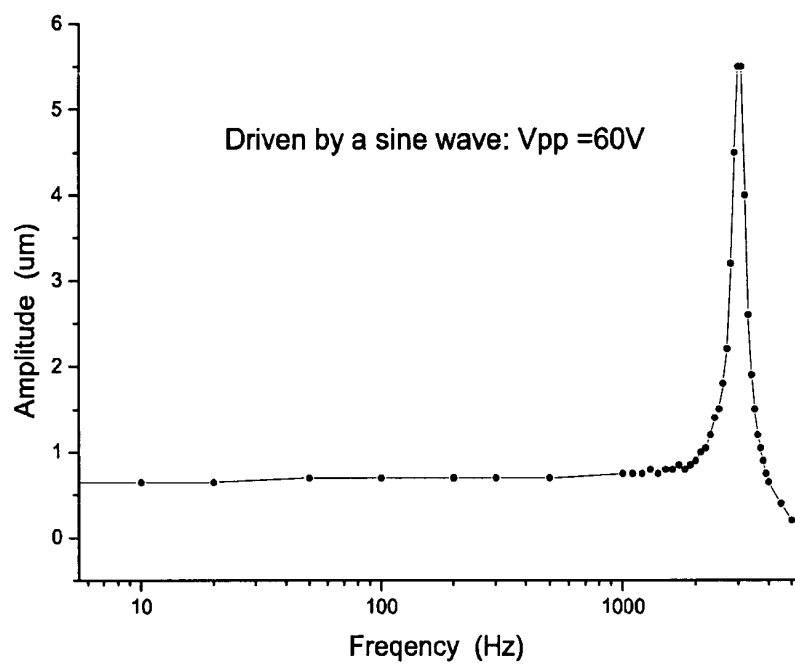
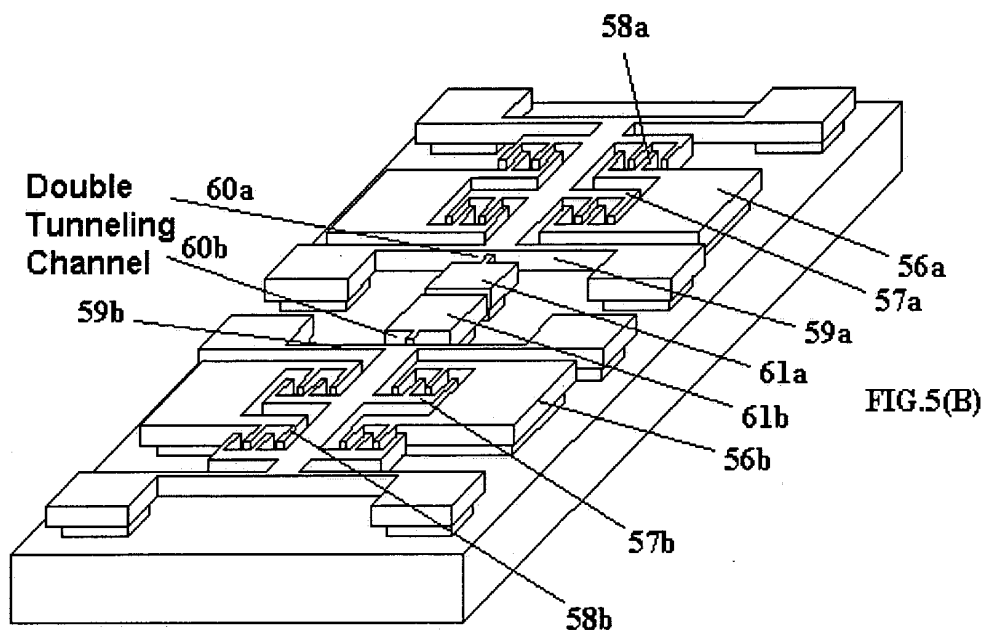
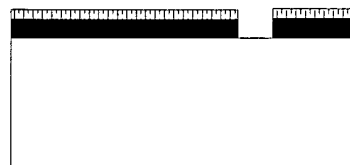


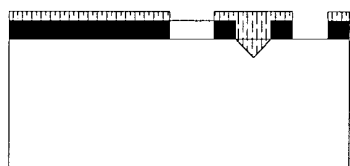
FIG.6



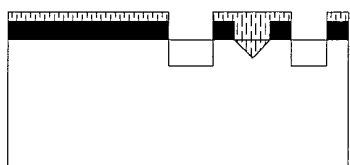
8 (a)



8 (b)

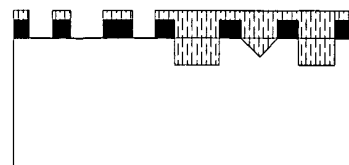


8 (c)

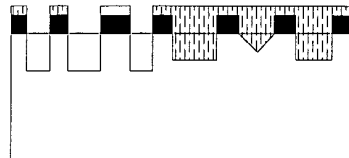


8 (d)

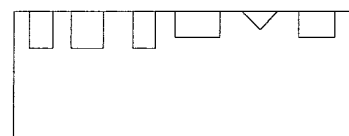
PR SiO₂



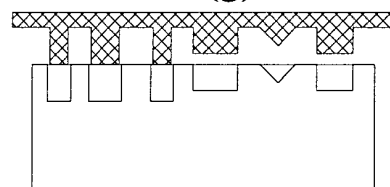
8 (e)



8 (f)

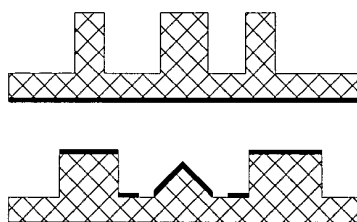


8 (g)



8 (h)

Si PMMA



8 (j)

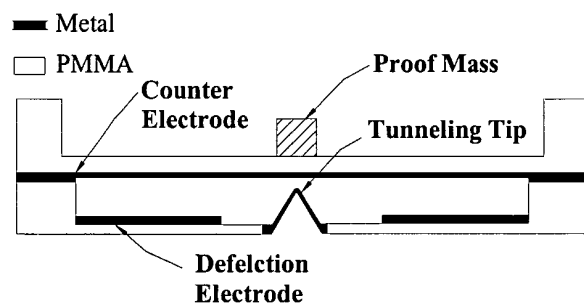


FIG. 8 (k)

Cross section of a membrane type PMMA-based tunneling sensor

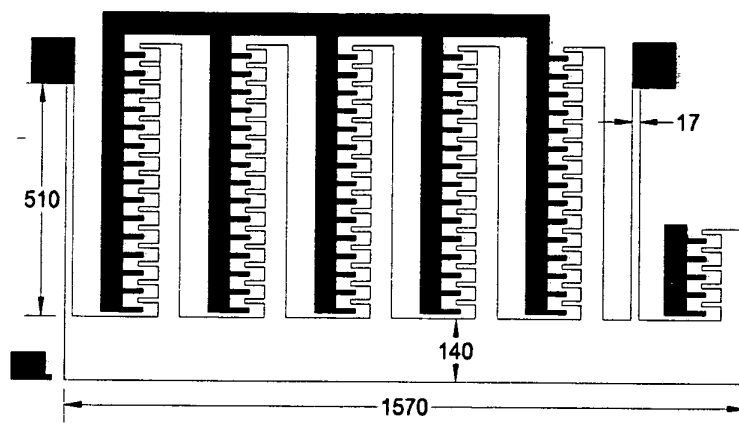


FIG. 7

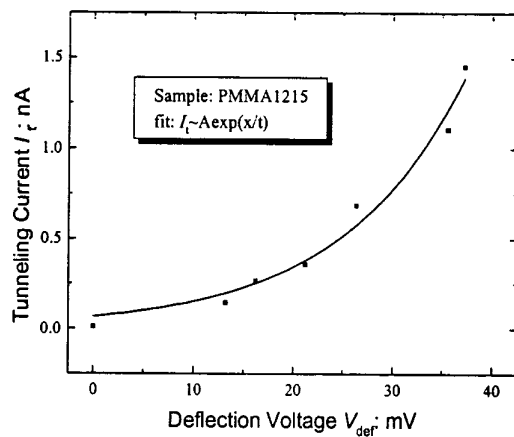


FIG. 9 The exponential relationship between tunneling currents and applied deflection voltages